

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Masahiko NAKAMORI, et al.
App. No	:	10/536621
Filed	:	May 26th, 2005
For	:	POLISHING PAD AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE
Examiner	:	Sylvia R. MacArthur
Art Unit	:	1792
Conf #	:	9275

AMENDMENT AFTER FINAL**Mail Stop AF**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed June 2nd, 2008, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.